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Results 11 - 20 of about 3,690 for wireless sensor electrically conductive loop permanent magn. t. (0.21 seconds)

[Homopolar Generator](#)

... direct measurement of generator driving torque  $\propto$  rpm from an in-line torque **sensor**.  
 ... (1) Nikola Tesla; The **Electrical Engineer**, NY ... 2) **Wireless** Engineer, November  
 ...  
[www.gocs1.com/gocs1/Psonics/Homopolar-Generator.htm](http://www.gocs1.com/gocs1/Psonics/Homopolar-Generator.htm) - 22k -  
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... as open-loop with closed-loop correction based ... **Sensors** are provided for measuring the excitation voltage ... are induced in the **electrically conductive** material of ...  
[michigan.craintech.com/cgi-bin/article.pl?articleId=3532](http://michigan.craintech.com/cgi-bin/article.pl?articleId=3532) - 101k -  
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 ... would also be useful for **wireless** microsensor networks ... This overlap insures the **electrical** connectivity necessary for ... **Sensors** and **Actuators A** 97±98 (2002) 88 ...  
[www.ee.ucla.edu/~judy/publications/journal/sensors\\_and\\_actuators\\_A\\_2002\\_yang\\_judy.pdf](http://www.ee.ucla.edu/~judy/publications/journal/sensors_and_actuators_A_2002_yang_judy.pdf) - [Similar pages](#)  
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[\[DOC\] Technical Program Schedule](#)

File Format: Microsoft Word 2000 - [View as HTML](#)  
 ... 3890. **Electrical** Performance Test Procedure for Uninterruptible Power ...  
 Adjustment of Resonant Loop Antennas in ... Location Algorithm for **Wireless Sensor** Networks in ...  
[www.icit2004.com/finalProgram\\_files/Preliminary.doc](http://www.icit2004.com/finalProgram_files/Preliminary.doc) - [Similar pages](#)

[Auto Parts 101: Electrical Systems](#)

... the amount of light on the **sensor**-amplifier ... Electronics refers to any **electrical** component, assembly, circuit, or ... one direction and remain non **conductive** in the ...  
[www.partsamerica.com/Auto101elec.asp](http://www.partsamerica.com/Auto101elec.asp) - 52k - [Cached](#) - [Similar pages](#)

[The Electrical System](#)

... in one direction and remain non **conductive** in the ... from the crankshaft **sensor** and the camshaft **sensor**. ... Almost everything that is powered **electrically** in your ...  
[www.autoshop-online.com/auto101/electext.html](http://www.autoshop-online.com/auto101/electext.html) - 90k - [Cached](#) - [Similar pages](#)

[\[PDF\] TECHNOLOGY INNOVATION](#)

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 ... Transceivers for Low Duty Cycle **Wireless Sensor** Networks ... Architecture for Real-time **Sensor** Analysis and ... statistical method to minimize **electrical** energy losses ...  
[eerc.up.ac.za/~ieee/AFRICON%202004%20CONFERENCE%20PROGRAMME.pdf](http://eerc.up.ac.za/~ieee/AFRICON%202004%20CONFERENCE%20PROGRAMME.pdf) - [Similar pages](#)

[Magnetic fields \(EHC 69, 1987\)](#)

... are related by the specific **conductivity** of the ... Using thin-film Hall **sensors** that record **magnetic** ... This dosimeter uses **electrically-shielded**, 500-turn copper ...  
[www.mindcontrolforums.com/magnetic-fields-EHC-69-1987.htm](http://www.mindcontrolforums.com/magnetic-fields-EHC-69-1987.htm) - 101k -  
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[IFAC Keyword list](#)

... breakdown characteristics conduction **conductivity** contacts feedback ... Game theory Gap **critical** machines elements ... analysis functions **Sensor** failures fusion  
 ...  
[www.autsubmit.com/documents/keywords.html](http://www.autsubmit.com/documents/keywords.html) - 68k - [Cached](#) - [Similar pages](#)

[CDSP THESES](#)

... Techniques for Contactless **Electrical Conductivity** Imaging ... for CDMA  
Broadband **Wireless** Integrated Services ... Miller Xuehu Zhang - Remotely **S** nsing  
the Chesapeake ...  
[www.cdsp.neu.edu/workshop/theses.html](http://www.cdsp.neu.edu/workshop/theses.html) - 75k - [Cached](#) - [Similar pages](#)

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**1 Ink-jet printed nanoparticle microelectromechanical systems**

*Fuller, S.B.; Wilhelm, E.J.; Jacobson, J.M.;*

Microelectromechanical Systems, Journal of, Volume: 11, Issue: 1, Feb. 2000  
Pages:54 - 60

[\[Abstract\]](#) [\[PDF Full-Text \(171 KB\)\]](#) **IEEE JNL**

**2 Microelectromechanical filters for signal processing**

*Lin, L.; Nguyen, C.T.-C.; Howe, R.T.; Pisano, A.P.;*

Micro Electro Mechanical Systems, 1992, MEMS '92, Proceedings. 'An Investigation of Micro Structures, Sensors, Actuators, Machines and Robot'. IEEE, 4-7 Feb.

Pages:226 - 231

[\[Abstract\]](#) [\[PDF Full-Text \(516 KB\)\]](#) **IEEE CNF**

**3 A highly flexible design and production framework for modularized microelectromechanical systems**

*Schuenemann, M.; Grosser, V.; Leutenbauer, R.; Bauer, G.; Schaefer, W.; Reh, H.;*

Micro Electro Mechanical Systems, 1998. MEMS 98. Proceedings., The Eleventh Annual International Workshop on, 25-29 Jan. 1998

Pages:597 - 602

[\[Abstract\]](#) [\[PDF Full-Text \(896 KB\)\]](#) **IEEE CNF**

**4 Test structures for determining design rules for microelectromechanical sensors and actuators**

*Zincke, C.; Gaitan, M.; Zaghloul, M.E.; Linholm, L.W.;*

Microelectronic Test Structures, 1994. ICMTS 1994. Proceedings of the 1994 International Conference on, 22-25 March 1994

Pages:44 - 50

**5 CARMEL: Contamination And Reliability Analysis of MicroElectromechanical Layout**

*Kolpekwar, A.; Jiang, T.; Blanton, R.D.;*

Microelectromechanical Systems, Journal of , Volume: 8 , Issue: 3 , Sept. 199  
Pages:309 - 318

**6 Microelectromechanical filters for signal processing**

*Liwei Lin; Howe, R.T.; Pisano, A.P.;*

Microelectromechanical Systems, Journal of , Volume: 7 , Issue: 3 , Sept. 199  
Pages:286 - 294

**7 A computer-aided design system for microelectromechanical system (MEMCAD)**

*Senturia, S.D.; Harris, R.M.; Johnson, B.P.; Kim, S.; Nabors, K.; Shulman, M. White, J.K.;*

Microelectromechanical Systems, Journal of , Volume: 1 , Issue: 1 , March 199  
Pages:3 - 13

**8 Microelectromechanical systems**

*Gabriel, K.J.;*

Proceedings of the IEEE , Volume: 86 , Issue: 8 , Aug. 1998  
Pages:1534 - 1535

**9 Air-channel fabrication for microelectromechanical systems via sacrificial photosensitive polycarbonates**

*Jayachandran, J.P.; Reed, H.A.; Hongshi Zhen; Rhodes, L.F.; Henderson, C.L. Allen, S.A.B.; Kohl, P.A.;*

Microelectromechanical Systems, Journal of , Volume: 12 , Issue: 2 , April 2000  
Pages:147 - 159

**10 The strain gradient effect in microelectromechanical systems (MEMS)**

*Zhenyu Xue; Saif, M.T.A.; Yonggang Huang;*

Microelectromechanical Systems, Journal of , Volume: 11 , Issue: 1 , Feb. 2000  
Pages:27 - 35

**11 An extraction-based verification methodology for MEMS**

*Baidya, B.; Gupta, S.K.; Mukherjee, T.;*

Microelectromechanical Systems, Journal of , Volume: 11 , Issue: 1 , Feb. 2000  
Pages:2 - 11

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**12 Fabrication of air-channel structures for microfluidic, micro electromechanical, and micro electronic applications**

*Bhusari, D.; Reed, H.A.; Wedlake, M.; Padovani, A.M.; Allen, S.A.B.; Kohl, P.A.*  
Microelectromechanical Systems, Journal of, Volume: 10, Issue: 3, Sept. 2000  
Pages:400 - 408

[\[Abstract\]](#) [\[PDF Full-Text \(216 KB\)\]](#) [IEEE JNL](#)

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**13 Microelectromechanical digital-to-analog converters of displacement step motion actuators**

*Toshiyoshi, H.; Kobayashi, D.; Mita, M.; Hashiguchi, G.; Fujita, H.; Endo, J.; Ito, Y.;*  
Microelectromechanical Systems, Journal of, Volume: 9, Issue: 2, June 2000  
Pages:218 - 225

[\[Abstract\]](#) [\[PDF Full-Text \(716 KB\)\]](#) [IEEE JNL](#)

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**14 A system for automatic electrical and optical characterization of microelectromechanical devices**

*Burns, D.J.; Helbig, H.F.;*  
Microelectromechanical Systems, Journal of, Volume: 8, Issue: 4, Dec. 1999  
Pages:473 - 482

[\[Abstract\]](#) [\[PDF Full-Text \(752 KB\)\]](#) [IEEE JNL](#)

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**15 Extension of the boundary element method to systems with conductors and piece-wise constant dielectrics**

*Vallishayee, R.R.; Cho, D.D.;*  
Microelectromechanical Systems, Journal of, Volume: 5, Issue: 3, Sept. 1996  
Pages:221 - 227

[\[Abstract\]](#) [\[PDF Full-Text \(468 KB\)\]](#) [IEEE JNL](#)

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